

Inventor: Craig M. Carpenter; Ross S. Dando

Title: Chemical Vapor Deposition Apparatuses and Deposition
Methods

Assignee: Micron Technology, Inc.

Attorney Docket No. MI22-1563



INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

REMARKS

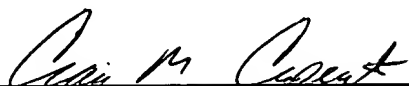
The citations listed, copies attached, may be material to the examination of the subject application and are therefore submitted in compliance with the duty of disclosure defined in 37 CFR §1.56. The Examiner is requested to make these citations of official record in this application. No admission is made regarding whether all the submitted references are prior art.

The materials cited are presented to assist in and expedite examination of this application. The present invention is considered to be patentable over the cited materials. Expeditious examination and allowance of this application as a patent are therefore urged in order that the public may benefit from the disclosure and commercialization of the invention.


EL 465855490

R spectfully submitted,

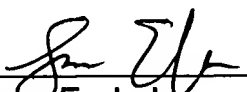
Dated: 1 MARCH 2001

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Dated: 3 March 2001

Inventor: 
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Dated: 13 Mar 2001

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1563	SERIAL NO. Filed Herewith		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Craig M. Carpenter; Ross S. Dando			
				FILING DATE Filed Herewith			
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,983,906	11/16/99	Zhao et al			
	AB						
	AC						
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	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
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						Yes	No
	AM						
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
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